

Semiconductor Parametric Test System



- > Overview of Equipment
- v Features

Batch processing of multiple DUTs

Simultaneously applies stress to and measures up to 108 SMUs on the package level and up to 324 SMUs on the wafer level.

Number of DUT processes

Evaluation	Number of setting terminals	Number of DUT processes	
		Wafer 324 SMU (36 SMU × 9 Sets)	Package 108 SMU (36 SMU × 3 Sets)
FET evaluation TDDB evaluation	4 terminal test	Max. 81 DUT	Max. 27 DUT
FET evaluation TDDB evaluation	2 terminal test	Max. 162 DUT	Max. 54 DUT
TDDB evaluation	1 terminal test	Max. 324 DUT	Max. 108 DUT

* Additional software (optional) is required to perform TDDB evaluation.

Highly-accurate application and measurement of voltage and current

The accuracy of the multi SMU has a range of 2 voltages and 9 currents at ±50 V/±100 mA, and the system can apply and measure a wide range with a resolution of 1 mV/1 pA.

FET single unit transistor characteristics support TDDB evaluation

Using the 2-terminal (Drain/Gate) and 4-terminal (Drain/Gate/Base/Source) settings, the FET single unit transistor can evaluate I-V characteristics, HCI, and NBTI.

In addition, the optional TDDB evaluation software can be used to evaluate TDDB, TZDB, SBD, QDB, I-V, BDV, and more.

Use software to change pin assignments

Change the terminal settings by cabinet (36 SMUs × 3 sets). In addition, changes can be made to the pad layout for the same number of terminals on the application for each multi SMU, thereby enabling changes to the pin assignments with the same probe guard.

Avoid electrostatic breakdown

To avoid static electricity from human bodies, a short connector is provided that prevents damage to the FET. The wiring on the DUT board is guarded to the socket source so as not to be affected by electrical noise. (Package level evaluation)



DUT board with short connector (test area)

Recommended products for customers viewing this product

Bench-top Type
Temperature
(& Humidity)
Chamber



Temperature
Chamber Series



Mini-subzero
Compact Ultra Low
Temperature
Chamber

